

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

First Named
Inventor :

Benjamin Y.H. Liu et al.

Appln. No. : 10/769,011

Filed : January 30, 2004

Group Art Unit: 1763

For : HIGH-PERFORMANCE AND MULTI-
LIQUID-PRECURSOR
VAPORIZATION IN
SEMICONDUCTOR THIN FILM
DEPOSITION

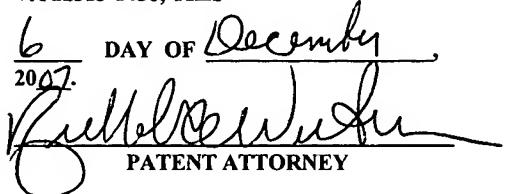
Examiner: Richard Bueker

Docket No.: M419.12-0043

REQUEST FOR APPROVAL OF FORMAL DRAWINGS

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I HEREBY CERTIFY THAT THIS PAPER
IS BEING SENT BY U.S. MAIL, FIRST
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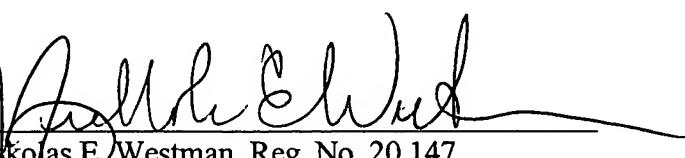
6 DAY OF December,
2007.

PATENT ATTORNEY

Sir:

Enclosed are **Eight (8)** sheets of formal drawings for filing in the above-identified application.

Respectfully submitted,

WESTMAN, CHAMPLIN & KELLY, P.A.

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NEW:rkp